



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE  
United States Patent and Trademark Office  
Address: COMMISSIONER OF PATENTS AND TRADEMARKS  
Washington, D.C. 20231  
www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/026,470	12/27/2001	Derek Tam	1875.1350000	7771

28393 7590 04/24/2003

STERNE, KESSLER, GOLDSTEIN & FOX P.L.L.C.  
1100 NEW YORK AVE., N.W.  
WASHINGTON, DC 20005

EXAMINER

MALSAWMA, LALRINFAMKIM HMAR

ART UNIT PAPER NUMBER

2825

DATE MAILED: 04/24/2003

Please find below and/or attached an Office communication concerning this application or proceeding.

# Office Action Summary

Application No.

10/026,470

Applicant(s)

TAM ET AL.

Examiner

Lex Malsawma

Art Unit

2825

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

## Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).
- Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

## Status

- 1) ☒ Responsive to communication(s) filed on 03 January 2003.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

## Disposition of Claims

- 4) ☒ Claim(s) 1-19 is/are pending in the application.
- 4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.
- 5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.
- 6) ☒ Claim(s) 1-19 is/are rejected.
- 7) ☐ Claim(s) \_\_\_\_\_ is/are objected to.
- 8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

## Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on \_\_\_\_\_ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
- Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
- 11) ☐ The proposed drawing correction filed on \_\_\_\_\_ is: a) ☐ approved b) ☐ disapproved by the Examiner.
- If approved, corrected drawings are required in reply to this Office action.
- 12) ☐ The oath or declaration is objected to by the Examiner.

## Priority under 35 U.S.C. §§ 119 and 120

- 13) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some \* c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- \* See the attached detailed Office action for a list of the certified copies not received.
- 14) ☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).
- a) ☐ The translation of the foreign language provisional application has been received.
- 15) ☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.

## Attachment(s)

- 1) ☒ Notice of References Cited (PTO-892)
- 2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3) ☐ Information Disclosure Statement(s) (PTO-1449) Paper No(s) \_\_\_\_\_.
- 4) ☐ Interview Summary (PTO-413) Paper No(s) \_\_\_\_\_.
- 5) ☐ Notice of Informal Patent Application (PTO-152)
- 6) ☐ Other: \_\_\_\_\_.

## DETAILED ACTION

### *Claim Rejections - 35 USC § 103*

1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

2. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

3. Claims 1-5 and 16-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ohwa (6,303,957 B1) in view of Tarabbia et al. (6,351,020 B1, hereinafter "Tarabbia").

#### *Regarding Claims 1 and 16:*

Ohwa discloses (in Fig. 2 and col. 11, line 48 to col. 12, line 18) a semiconductor device (and method of making the device) comprising:

- an N-type substrate 204;
- a P-type region 208 within the N-type substrate;
- a thick oxide 218 formed over said P-type region;

a gate electrode 222 formed over said thick oxide and coupled to a first voltage supply line; and

P<sup>+</sup> pick-up terminals (214, 216) within said P-type region adjacent the gate electrode and coupled to a second voltage supply line; and

whereby said semiconductor device functions as a capacitor during operations.

Ohwa **lacks** the gate electrode being doped P<sup>+</sup>. Tarabbia **teaches** a MOS capacitor structure, similar to that disclosed by Ohwa, formed with both N-type terminals and P-type terminals (note Tarabbia, col. 4, lines 24-45). In column 4 (lines 4-7), Tarabbia discloses the impurity type for the top plate depends on whether a P-type or an N-type capacitor is being formed (Note: the top plate would be the gate electrode within the MOS capacitor). It would have been obvious to one of ordinary skill in the art to modify Ohwa by forming a P<sup>+</sup> gate electrode because Tarabbia teaches such a modification would depend on the type of capacitor being formed, i.e., Tarabbia teaches using P-type impurities when specifically forming P-type capacitors.

*Regarding Claim 2:*

This claim contains a limitation for some specific application/use of the device of Claim 1. Since Ohwa (in view of Tarabbia) discloses the device of Claim 1, it would have been obvious to one of ordinary skill in the art to modify Ohwa (in view of Tarabbia) by specifically reciting a gate-to-substrate voltage because the device would be utilized according to design needs, i.e., one could have easily specified a gate-to-substrate voltage equal to zero volts, or greater than zero volts, or slightly greater than zero volts, etc., wherein a specific voltage would depend on a particular design/application.

*Regarding Claims 3-5 and 17-19:*

Ohwa discloses the gate comprises polysilicon (col. 12, lines 5-6); the N-type substrate 204 comprises a deep well (Fig. 21 and col. 11, lines 53-61); and the gate oxide typically having a thickness of 50-200 Å (col. 10, lines 24-25).

4. Claims 6-15 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ohwa (6,303,957 B1) in view of Tarabbia (6,351,020 B1), Applicant admitted prior art (hereinafter "APA"), and Kriedt et al. (4,335,359, hereinafter, "Kriedt").

*Regarding Claims 6 and 11:*

These claims contain limitations for specifically integrating the capacitor of Claims 1-5 into a low-pass filter, wherein the low-pass filter is part of a phase locked loop (PLL) circuit. Note Ohwa (in view of Tarabbia) discloses all limitations of the capacitor. Furthermore, note that APA discloses (in Fig. 1 and pages 1-4) all elements of the PLL circuit specified in Claim 6, excluding the specific structure of the capacitor integrated into the low-pass filter. Kriedt is **cited only to show** it was very well known at the time the current invention was made to integrate a MOS capacitor into a low-pass filter circuit (note Kriedt, col. 2, lines 11-12). It would have been obvious to one of ordinary skill in the art to modify Ohwa (in view of Tarabbia) by specifically incorporating the capacitor into a low-pass filter circuit and further integrating the low-pass filter into a PLL circuit because Kriedt shows it was well known in the art to incorporate a MOS capacitor into a low-pass filter and APA shows it was well known in the art that a PLL circuit would include a low-pass filter. In other words, one of ordinary skill would have found it obvious to specifically integrate the MOS capacitor of Ohwa (in view of Tarabbia)

Art Unit: 2825

into any known circuitry such as the PLL circuit with a low-pass filter (as disclosed by APA), wherein the MOS capacitor could be specifically incorporated into the low-pass filter as shown by Kriedt.

*Regarding Claims 7-10 and 12-15:*

These claims are similar to Claims 2-5, which were specifically addressed above; therefore, they are held obvious over the cited references with reasoning similar to those applied to Claims 2-5 above.

***Conclusion***

5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

The references listed on the attached "Notice of References Cited" are cited to show MOS capacitors (and methods of forming them), a PLL circuit, charge pump, etc., having features similar to those of the current invention.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Lex Malsawma whose telephone number is 703-306-5986.


If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Matthew Smith can be reached on 703-308-1323. The fax phone numbers for the organization where this application or proceeding is assigned are 703-872-9318 for regular communications and 703-872-9319 for After Final communications.

Application/Control Number: 10/026,470

Page 6

Art Unit: 2825

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

  
CARIDAD EVERHART  
PRIMARY EXAMINER

Lex Malsawma 

April 21, 2003